Amendments to the claims:

1. (Canceled)

2. (Currently Amended) A microelectromechanical (MEMS) structure on a substrate, the MEMS structure comprising:

an actuator body connected with a suspension system; and

the suspension system connected with the substrate, the suspension system being configured to elevate the actuator body above the substrate in a motion substantially perpendicular to the substrate, the suspension system comprising:

a set of one or more flexures, each flexure connecting the actuator body with the substrate;

a set of one or more torsional elements, wherein each torsional element connects a corresponding flexure with the actuator body, comprises the only physical connection between the corresponding flexure and the actuator body, each torsional element having a length comprising the distance from the corresponding flexure to the actuator body, the length being greater than the width of the torsional element, wherein each torsional element is not ~~substantially~~ parallel to the substrate when the actuator body is elevated above the substrate in a motion substantially perpendicular to the substrate.

3. (Previously Presented) The MEMS structure of claim 2, wherein each torsional element relieves angular strain caused by a difference between the angle of the corresponding flexure and the angle of the actuator body.

4. (Previously Presented) The MEMS structure of claim 2, wherein each torsional element has an angle of twist per unit moment (θ/Nm) of 7.00E+06 or greater.

5. (Previously Presented) The MEMS structure of claim 2, wherein each torsional element has a length that extends from the corresponding flexure to the actuator body, the length having a value equal to or greater than 5μm and equal to or less than 20μm.

6. (Previously Presented) The MEMS structure of claim 2, wherein each torsional element has a width that extends perpendicular to its length and substantially parallel to the substrate, the width having a value equal to or greater than 2μm and less than 10μm.

7. (Previously Presented) The MEMS structure of claim 2, wherein a torsional element comprises a torsional attachment or a torsional spring.

8. (Previously Presented) The MEMS structure of claim 7, wherein a torsional element is shaped in a serpentine form.

9. (Canceled)

10. (Previously Presented) The MEMS structure of claim 2, wherein the actuator body is a platform, actuator segment, or mirror segment.

11. (Previously Presented) The MEMS structure of claim 2, wherein each torsional element extends from the corresponding flexure to the actuator body in a direction that is substantially perpendicular to the corresponding flexure.

12. (Previously Presented) The MEMS structure of claim 2, wherein the suspension system is configured to elevate the entirety of the actuator body above the substrate.

13. (Previously Presented) The MEMS structure of claim 2, wherein each torsional element has a width that is less than the width of the corresponding flexure at the anchor point.

14. (Previously Presented) The MEMS structure of claim 2, wherein each torsional element provides strain relief between a corresponding flexure and the actuator body.

15. (Previously Presented) The MEMS structure of claim 2, wherein the width of a torsional element is less than the width of the corresponding flexure.

16. (Previously Presented) The MEMS structure of claim 2, wherein:

the suspension system further comprises a set of one or more anchor points, wherein each anchor point connects a corresponding flexure to the substrate and has an angle of twist per unit moment value substantially equal to a first value; and

each torsional element has an angle of twist per unit moment value substantially equal to a second value, wherein the second value is greater than the first value.